

Title (en)

Method for avoiding depositions in vapour-systems

Title (de)

Verfahren zur Verhinderung von Ablagerungen in Dampfsystem

Title (fr)

Procédé pour éviter les dépôts dans un système à vapeur

Publication

**EP 1245795 A3 20041006 (DE)**

Application

**EP 02405180 A 20020311**

Priority

DE 10116034 A 20010330

Abstract (en)

[origin: EP1245795A2] Process for preventing deposition of impurities in steam systems comprises preventing the steam solubility of the impurities present in certain concentrations from being exceeded as a result of changes in temperature and/or pressure ratios within the steam system. An Independent claim is also included for a steam system for carrying out the above process. Preferred Features: The impurity is silicon dioxide. The steam system consists of steam cooling or steam injection of a gas turbine system. The temperature and/or pressure of the steam flowing through the steam system is adjusted to prevent the steam solubility of the impurities present in steam in certain concentrations from being exceeded.

IPC 1-7

**F01K 21/06**

IPC 8 full level

**F01K 21/06** (2006.01)

CPC (source: EP US)

**F01K 21/06** (2013.01 - EP US)

Citation (search report)

- [X] EP 0508387 A1 19921014 - MITSUBISHI HEAVY IND LTD [JP]
- [X] US 4492083 A 19850108 - MCCABE BARKMAN C [US], et al
- [A] US 4509332 A 19850409 - BELLOWS JAMES C [US]
- [A] US 4386498 A 19830607 - LEE PANG-KAI, et al
- [A] US 2595490 A 19520506 - SCHUBRING ARTHUR C, et al

Cited by

DE102005046721B3

Designated contracting state (EPC)

AT BE CH CY DE DK ES FI FR GB GR IE IT LI LU MC NL PT SE TR

DOCDB simple family (publication)

**EP 1245795 A2 20021002; EP 1245795 A3 20041006**; DE 10116034 A1 20021002; US 2002139118 A1 20021003; US 2006010877 A1 20060119

DOCDB simple family (application)

**EP 02405180 A 20020311**; DE 10116034 A 20010330; US 10610502 A 20020327; US 16915605 A 20050629